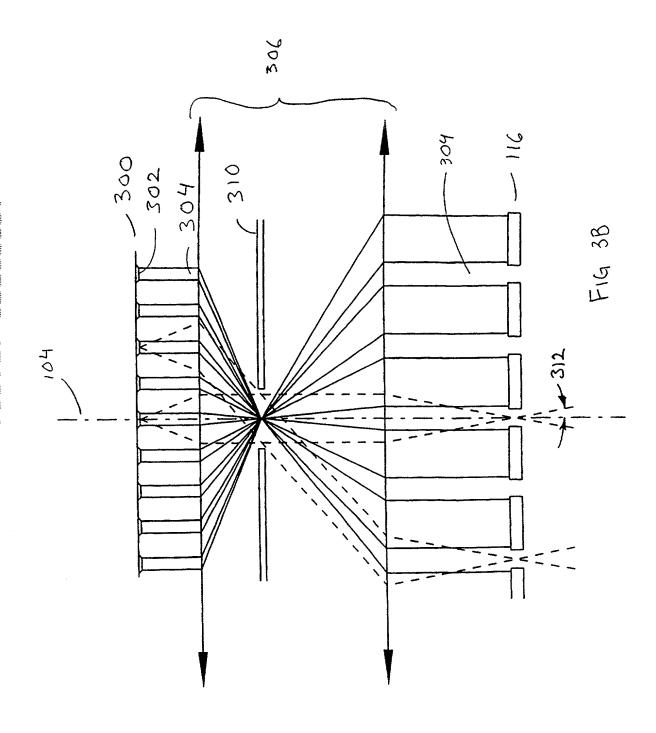


FIG. 4



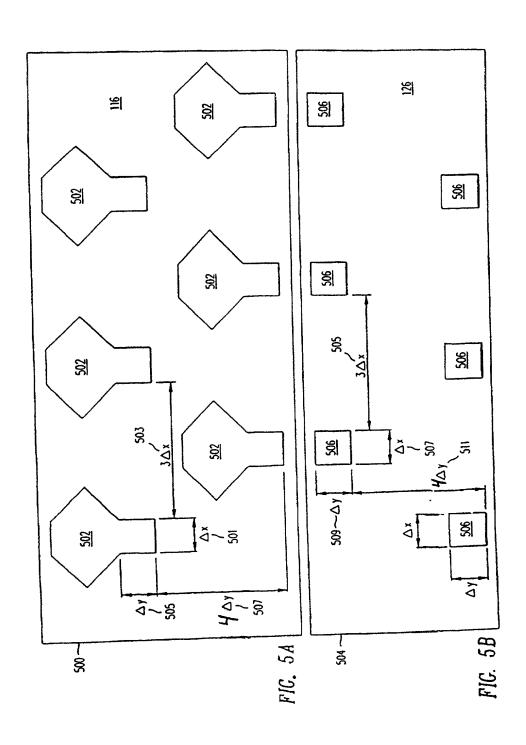
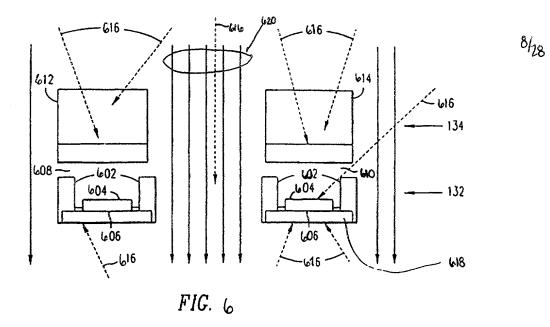
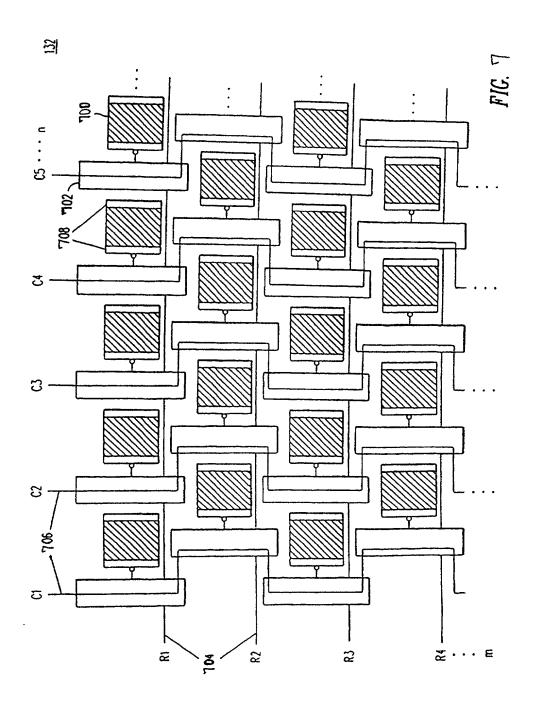


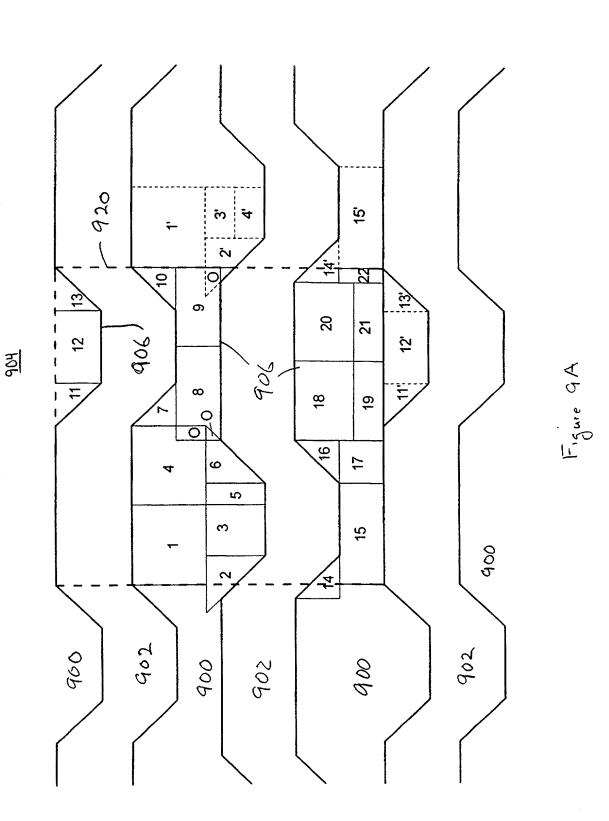
FIG. 5H



804 7 800 x

FIG. 8





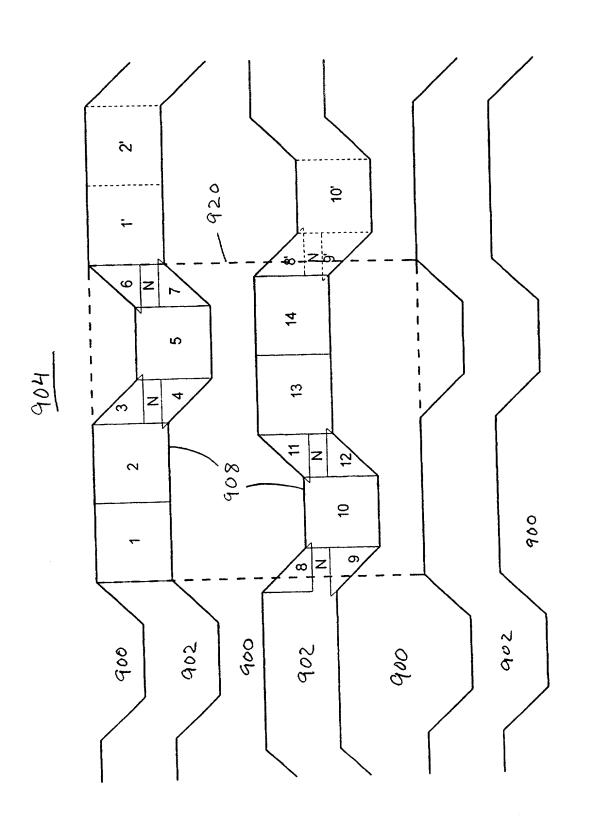
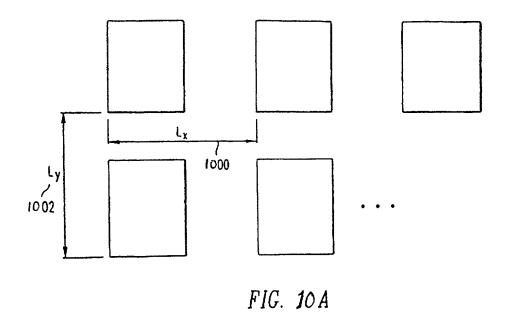


Figure 9B



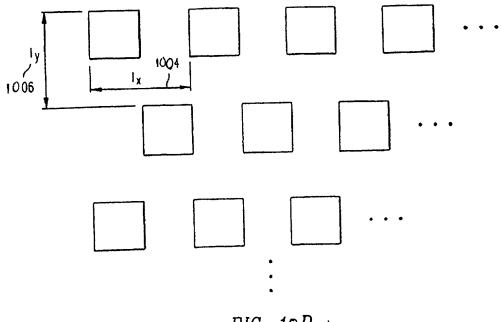
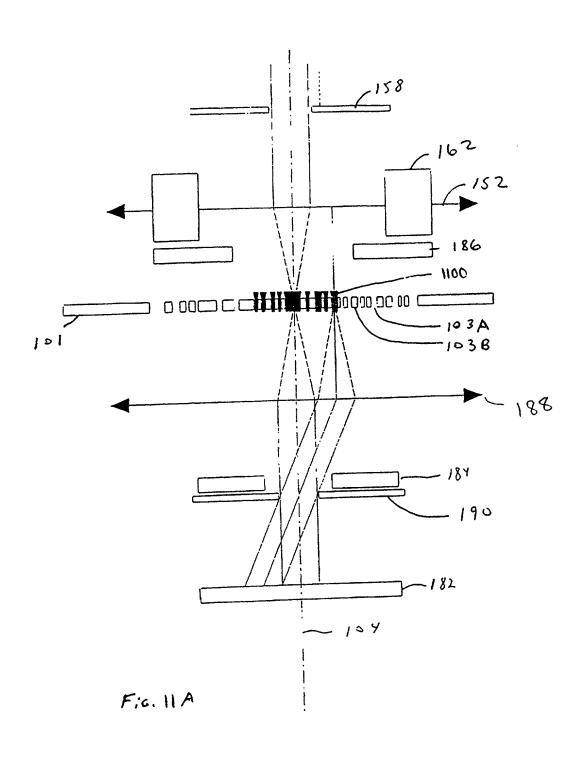
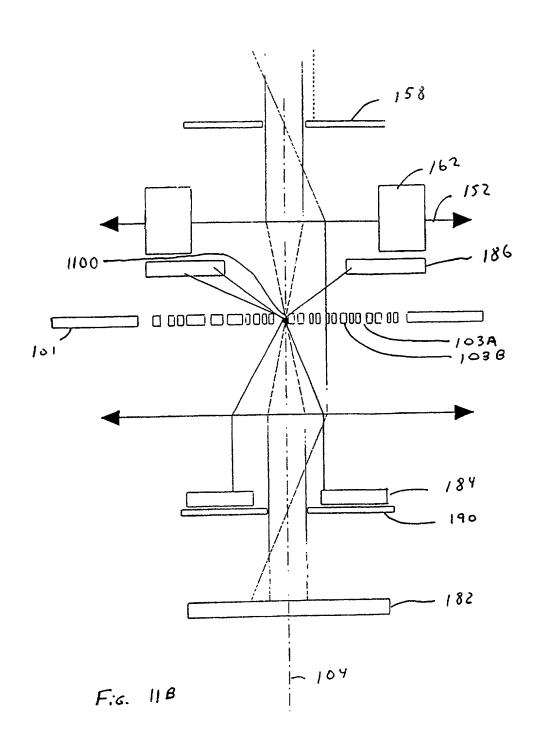
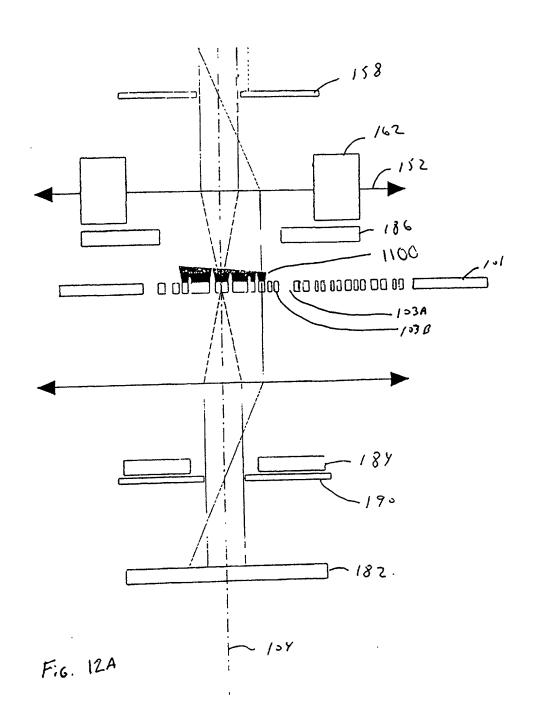
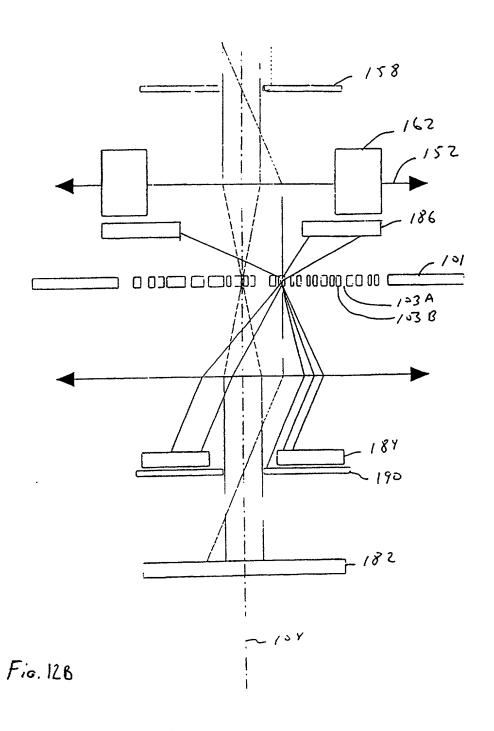


FIG. 10B

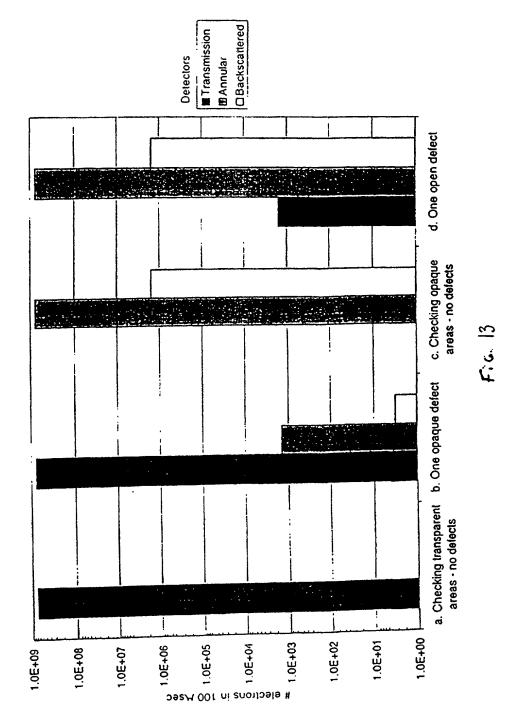


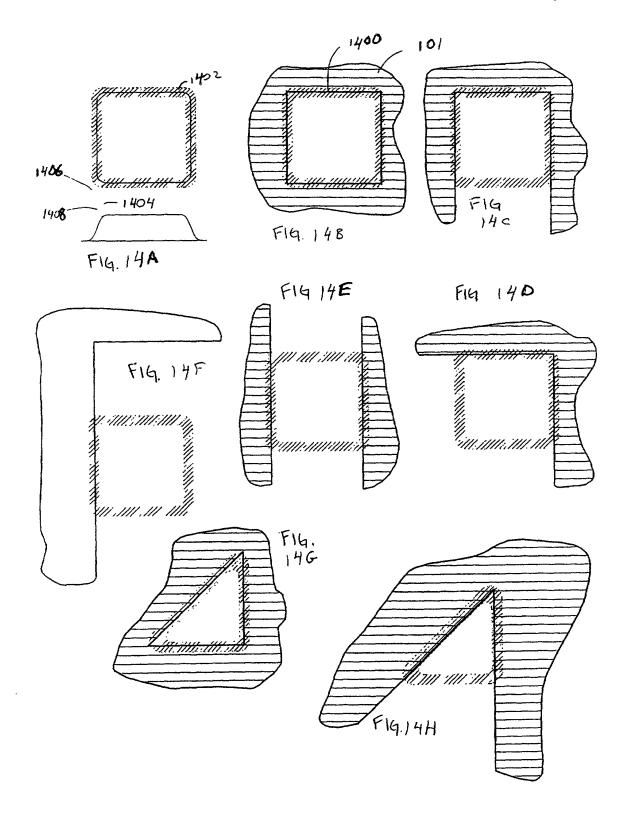


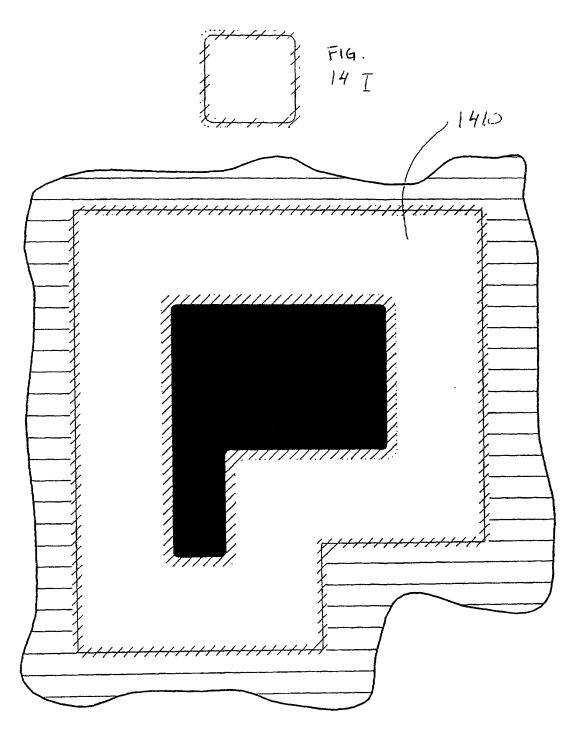






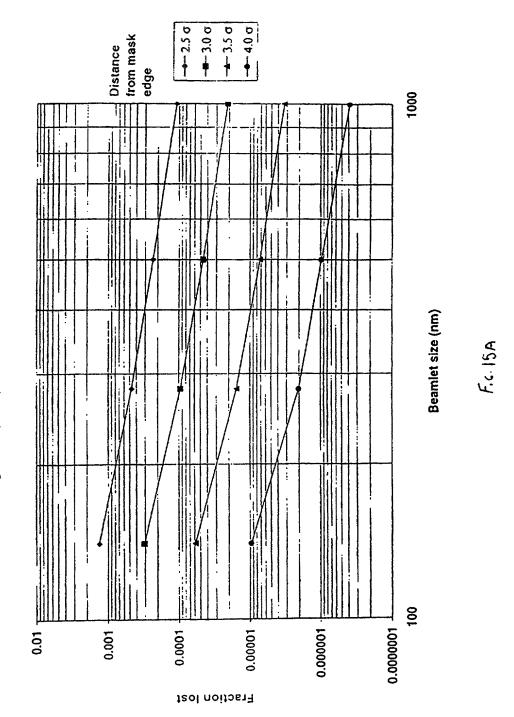




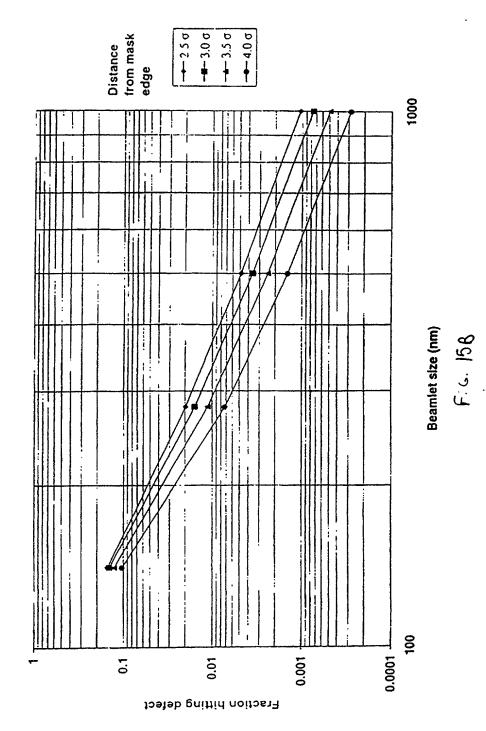


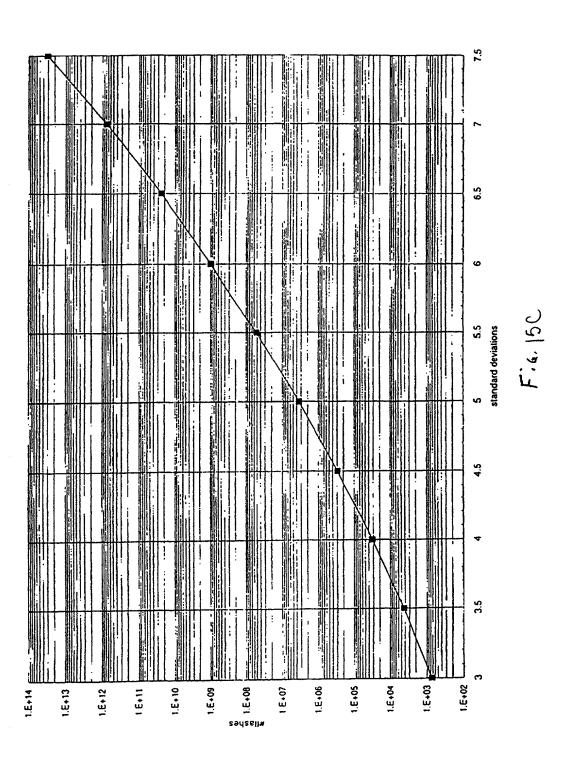
F19. 14J

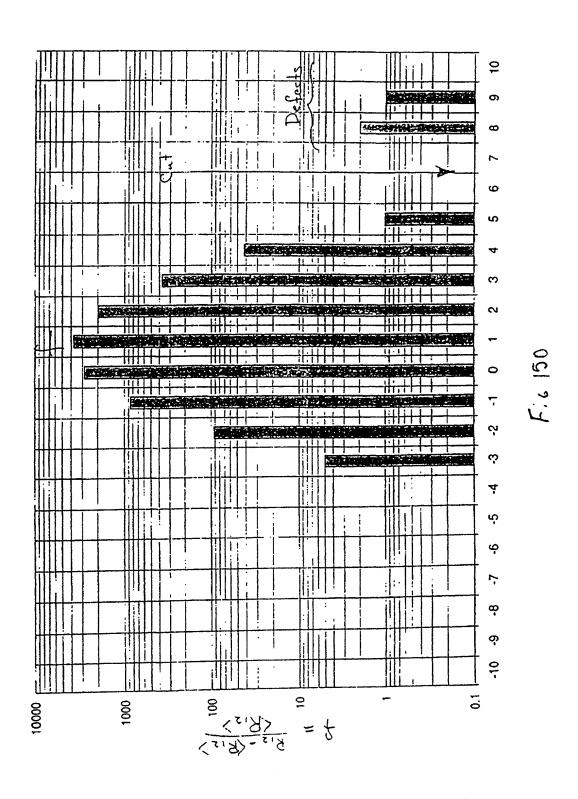
Fraction of beamlet lost on mask (on all four sides) edgewidth (12/88) = 30 nm; 1 σ = 12.77 nm



Fraction of beamlet hitting 50 nm defect edgewidth (12/88) = 30 nm; 1 s = 12.77 nm

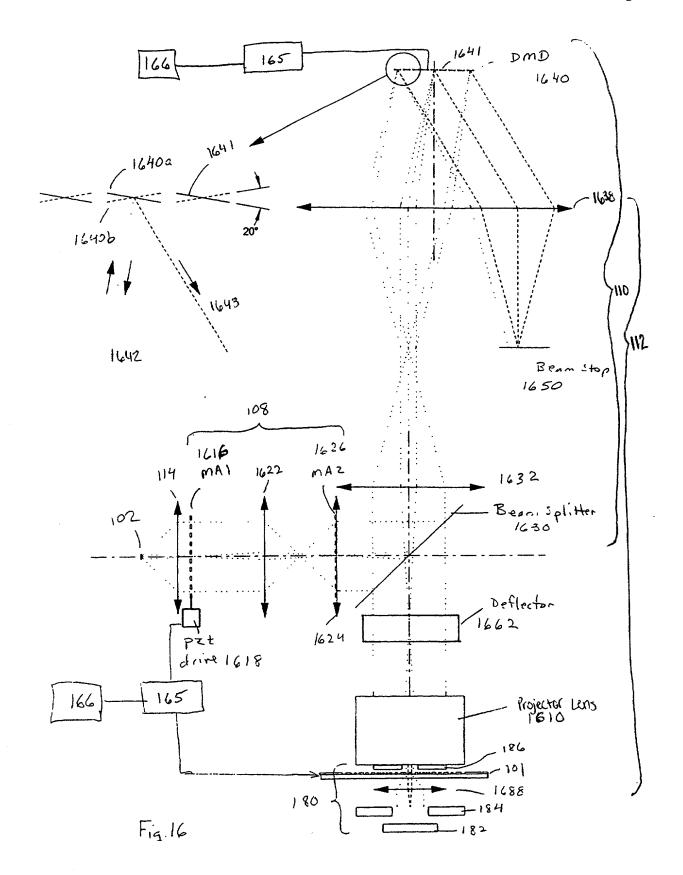






f/df for clear and opaque defects

24/28 -- 100 keV f/df opaque -B- 100 keV f/df clear --- 20 keV f/df clear F19 15E 0.1 0.08 Detector numerical aperture 90.0 0.04 0.02 20 15 25 10 Ŋ 0 ìb/ì



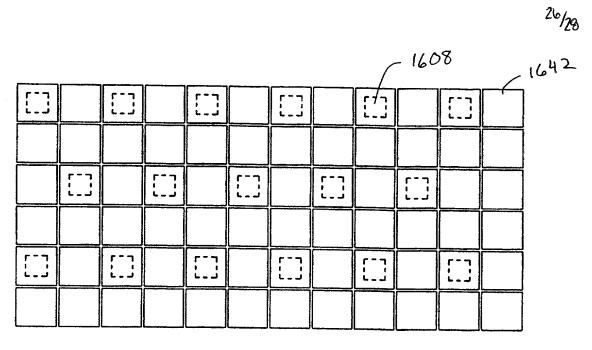
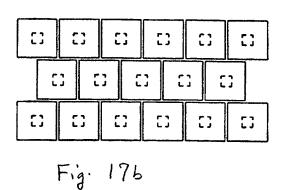


Fig. 17a



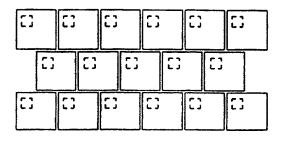


Fig. 17c

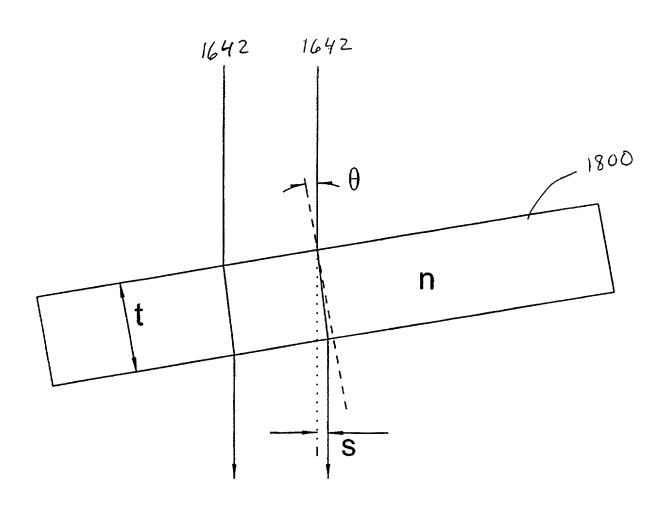


Fig 18

